



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Paul B. Mirkarimi et al. Docket No.: CIL-10972

Serial No. : 10/086,614 Art Unit : 1762

Filed: March 1, 2002 Examiner: W. Markham

For : Ion-Assisted Deposition Techniques For

The Planarization Of Topological Defects

## **AMENDMENT**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed February 16, 2005, please amend the above-referenced application as follows: